Express Mail No.EV335405653US Attorney Docket No. COVA0003 DIV Client/Matter No. 90337.0006.001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:			
Klaus Dimmler, Alfred P. Gnadinger	Group Art Unit:		
Serial No	Examiner:		
Filed: Herewith			
For: FERROELECTRIC TRANSISTOR WITH ENHANCED DATA RETENTION	Confirmation No.:		
Customer No. 25235			

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. 1.97

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

7/15/03

Sir:

Pursuant to 37 C.F.R. § 1.97, the Examiner may wish to consider the references listed on the attached Form PTO/SB/08A. In submitting these references, no representation is made or implied that the references are or are not material to the examination of this application.

This Information Disclosure Statement is filed before mailing of a first Office Action in the above case. Accordingly, no fee is believed due. However, any fee associated herewith may be charged to Deposit Account No. 50-1123.

Respectfully submitted,

Peter J. Meza, Reg. No. 32,920 HOGAN & HARTSON LLP

One Tabor Center

1200 17th Street, Suite 1500

Denver, Colorado 80202

(719) 448-5906 Tel (303) 899-7333 Fax

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PTO/SB/08A (10/01) (Substitute for form 1449A/PTO)	ATTY. DOCKET NO. COVA0003 DIV Client/Matter No. 90337.0006.001 APPLICATION NO		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	FIRST NAMED INVENTOR Klaus Dimmler, Alfred P. Gnadinger		
(Use several sheets if necessary) Sheet1 of5	FILING DATE Herewith	ART UNIT	

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